



PTO/SB/08a/b (08-03)

Approved for use through 07/31/2008. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Complete if Known	
				Application Number	10/798,822
				Filing Date	March 11, 2004
				First Named Inventor	Cyganski, David
				Art Unit	Not Yet Assigned 1756
				Examiner Name	Not Yet Assigned Caleen O. Sullivan
Sheet	1	of	3	Attorney Docket Number	WP9-001

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
/CS/	A1	4,734,746	03-29-1998	Ushida, <i>et al.</i>	
/CS/	A2	5,814,414	09-29-1998	Georger, <i>et al.</i>	
/CS/	A3	6,267,913	07-31-2001	Marder, <i>et al.</i>	
/CS/	A4	6,485,895	11-26-2002	Choi, <i>et al.</i>	
/CS/	A5	6,586,329	07-01-2003	Tanaka, <i>et al.</i>	
/CS/	A6	6,656,816	12-02-2003	Tomioka	
/CS/	A7	6,670,104	12-30-2003	Kido	
/CS/	A8	6,684,785	02-03-2004	Harwood	
/CS/	A9	6,686,300	02-03-2004	Mehrotra, <i>et al.</i>	
/CS/	A10	RD 437031	09-10-2000	3M, <i>et al.</i>	

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
/CS/	A11	JP 7150078	06-13-1995	Sekisui Chem Co Ltd		
/CS/	A12	WO 00/49080	08-24-2000	Chen Yaohong (CA), <i>et al.</i>		
/CS/	A13	WO 01/31401	05-03-2001	Najafi S Iraj (CA), <i>et al.</i>		
/CS/	A14	WO 02/40602	05-23-2002	CIBA Specialty Chemical Holdings, Inc.		
/CS/	A15	WO 02/19407	03-07-2002	Boukherroub, R., <i>et al.</i>		
/CS/	A16	WO 02/079691	10-10-2002	Kuebler, S.M., <i>et al.</i>		
/CS/	A17	WO 02/091433	11-14-2002	Infineon Technologies AG		

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

Examiner Signature	/Caleen Sullivan/ (05/18/2007)	Date Considered	
--------------------	--------------------------------	-----------------	--

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/B/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Application Number	10/798,822
				Filing Date	March 11, 2004
				First Named Inventor	Cyganski, David
				Art Unit	Not Yet Assigned 1756
				Examiner Name	Not Yet Assigned Caleen O. Sullivan
Sheet	2	of	3	Attorney Docket Number	WP9-001

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
/CS/	B1	Barnett, S.M., "Photonic de Broglie wave interferometers." <i>Journal of Modern Optics</i> . 1998; 45(11):2217-32.	
/CS/	B2	Boto, A.N., et al., "Quantum Interferometric Optical Lithography: Exploiting Entanglement to Beat the Diffraction Limit." <i>Physical Review Letters</i> . 2000 Sep; 85(13):2733-36.	
/CS/	B3	Fonseca, E.J.S., et al., "Measurement of the de Broglie Wavelength of a Multiphoton Wave Packet." <i>Physical Review Letters</i> . 1999 Apr; 82(14):2868-71.	
/CS/	B4	Gannon, T., et al., "Two-Laser-Sensitized Decomposition of Carbon Tetrachloride Photoacid Generation." <i>J. Org. Chem.</i> 1993; 58:5639-42.	
/CS/	B5	Jacobson, J., et al., "Photonic de Broglie Waves." <i>Physical Review Letters</i> . 1995 Jun; 74(24):4835-38.	
/CS/	B6	Lim, M., et al., "Confocality condition in two-color excitation microscopy with two focused excitation beams." <i>Optics Communications</i> . 2002; 207:121-30.	
/CS/	B7	McGimpsey, W.G., et al., "A Two-Photon Study of the "Reluctant" Norrish Type I Reaction of Benzil." <i>Journal of the American Chemical Society</i> . 1987; 109:2179-81.	
/CS/	B8	Nagasko, E.M., et al., "Nonclassical two-photon interferometry and lithography with high-gain parametric amplifiers." <i>Physical Review A</i> , 2001; 64:043802-1-043802-5.	
/CS/	B9	Pittman, T.B., et al., "Two-photon geometric optics." <i>Physical Review A</i> . 1996 Apr; 53(4):2804-15.	
/CS/	B10	Scaiano, J.C., et al., "Two-Laser, Two-Color Photochemistry from Upper Triplet States of 2-Bromonaphthalene and 9-Bromophenanthrene in Benzene." <i>J. Phys. Chem.</i> 1994; 98:5431-34.	
/CS/	B11	Smith, G.A., et al., "Two-Laser Photochemistry of Phenothiazine in Solution: Ionization and Bond Cleavage from Upper States." <i>J. Phys. Chem.</i> 1994; 98:2923-29.	
/CS/	B12	Steuernagel, O., "Scheme for fourfold de Broglie wavelength reduction of a multi-photon wavepacket." <i>J. Opt. B: Quantum Semiclass. Opt.</i> 4. 2002; S397-S400.	
/CS/	B13	Stekalov, D.V., et al., "Two-Photon Interferometry for High-Resolution Imaging." <i>J. Mod. Optic.</i> 2002; 49:519-27.	
/CS/	B14	Strickler, J.H., et al., "3-D Optical Data Storage by Two-Photon Excitation." <i>Adv. Mater.</i> 1993; 5(6):479-81.	
/CS/	B15	Wang, I., et al., "Three-dimensional microfabrication by two-photon-initiated polymerization with a low-cost microlaser." <i>Optics Letters</i> . 2002 Aug; 27(15):1348-50.	
/CS/	B16	Wang, Z., et al., "One- and Two-Laser Photochemistry of Iminodibenzyl." <i>J. Phys. Chem.</i> 1993; 97:9668-72.	
/CS/	B17	Wu, P.W., et al., "Two-photon exposure of photographic film." <i>J. Opt. Soc. Am. B</i> . 1999 Apr; 16(4):605-8.	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Applicant's unique citation designation number (optional). ²Applicant is to place a check mark here if English language Translation is attached.

Examiner Signature	/Caleen Sullivan/ (05/18/2007)	Date Considered	
--------------------	--------------------------------	-----------------	--

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/B/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Application Number	10/798,822
				Filing Date	March 11, 2004
				First Named Inventor	Cyganski, David
				Art Unit	Not Yet Assigned 1756
				Examiner Name	Not Yet Assigned Caleen O. Sullivan
Sheet	3	of	3	Attorney Docket Number	WP9-001

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
/CS/	C1	Yablonovitch, E., <i>et al.</i> , "Optical projection lithography at half the Rayleigh resolution limit by two-photon exposure." <i>Opt. Eng.</i> 1999 Feb; 38(2):334-38.	
/CS/	C2	Zhang, B., <i>et al.</i> , "Photochemistry of 1,2-Dibromoethyl." <i>J. Phys. Chem.</i> 1994; 98:7022-28.	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Applicant's unique citation designation number (optional). ²Applicant is to place a check mark here if English language Translation is attached.

Examiner Signature	/Caleen Sullivan/ (05/18/2007)	Date Considered	
-----------------------	--------------------------------	--------------------	--



Express Mail Label No. EV 971 664 855 US Dated: October 5, 2006

PTO/SB/08a/b (07-06)

Approved for use through 09/30/2006. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/B/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet 1 of 1

Complete if Known

Application Number	10/798,822-Conf. #5042
Filing Date	March 11, 2004
First Named Inventor	David CYGANSKI
Art Unit	2020 1756
Examiner Name	Not Yet Assigned Caleen O. Sullivan
Attorney Docket Number	WP9-001

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
/CS/	1	US-6,879,376	04-12-2005	Case et al.	

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ³
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

Examiner Signature	/Caleen Sullivan/ (05/18/2007)	Date Considered	
-----------------------	--------------------------------	--------------------	--